FORM PTO-1449	ATTY. DOCKET NO.	APPLICATION NO.	CONFIRMATION NO.
LIST OF PATENTS AND PUBLICATIONS FOR APPLICANT'S INFORMATION DISCLOSURE STATEMENT	200312474-1	10/677,825	—
(Use several sheets if necessary)	APPLICANT: Michael Monroe t al.		
	FILING DATE: Herewith	GROUP: ~~Unkn.~~ 2873	

REFERENCE DESIGNATION **U.S. PATENT DOCUMENTS**

Class / SCh

EXAMINER INITIAL		DOCUMENT NUMBER	PUBLICATION DATE	NAME	Pages, Columns, Lines Where Relevant Passages or Figures Appear
	1A	5,583,688	12/1996	Hornbeck	359/291
	1B	5,650,881	07/1997	Hornbeck	359/871
	1C	5,919,548	07/1999	Barron et al.	428/138
	1D	6,025,951	02/2000	Swart et al.	359/245
	1E	6,121,552	09/2000	Brosnihan et al.	174/253
	1F	6,396,368	05/2002	Chow et al.	333/262
	1G	6,440,766	08/2002	Clark	438/52
	1H	6,469,330	10/2002	Vigna et al.	257/254
	1I	6,480,320	11/2002	Nasiri	359/291
	1J	6,523,961	02/2003	Ilkov et al.	353/99
	1K	20020039470	04/2002	Braun et al.	385/50

FOREIGN PATENT DOCUMENTS

		DOCUMENT NUMBER	PUBLICATION DATE	NAME OF PATENTEE OR APPLICANT	Pages/Columns/Lines Where Relevant Passages/Figures Appear	Check if Translation attached
	1L	EP1093143	04/2001	Lucent Tech Inc.		N/A
	1M	JP2000314634	07/2001	Lucent Tech Inc.		✓
	1N					
	1O					
	1P					

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	1Q	J.H. Smith et al., "Material and Processing Issues for the Monolithic Integration of Microelectronics with Surface-Micromachined Polysilicon Sensors and Actuators" SPIE, October 1995, Pages 1-10.
	1R	Oliver Brand, "CMOS-based MEMS/DTU PhD Course/Topics in Microelectronics", Physical Electronics Laboratory, ETH Zurich, http://www.iqe.ethz.ch/pel, slides A-2 through A-36.
	1S	J.H. Smith et al., "Embedded Micromechanical Devices for the Monolithic Integration of MEMS with CMOS", 1995 IEEE, Pages 609-612.

EXAMINER	DATE CONSIDERED
	8/26/04

PATENT APPLICATION

Sheet 2 of 2

FORM PTO-1449	ATTY. DOCKET NO.	APPLICATION NO.	CONFIRMATION NO.
LIST OF PATENTS AND PUBLICATIONS FOR APPLICANT'S INFORMATION DISCLOSURE STATEMENT	200312474-1	10/677,825	—
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REFERENCE DESIGNATION **U.S. PATENT DOCUMENTS** Class/SCN

EXAMINER INITIAL		DOCUMENT NUMBER	PUBLICATION DATE	NAME	Pages, Columns, Lines Where Relevant Passages or Figures Appear
JJ	2A	20030034535	02/2003	Barenburg et al.	257/415
JJ	2B	5,485,304	01/1996	Kaeriyama	359/291
JJ	2C	5,631,782	05/1997	Smith et al.	359/871
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JJ	2F	6,038,056	03/2000	Florence et al.	359/290
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FOREIGN PATENT DOCUMENTS

		DOCUMENT NUMBER	PUBLICATION DATE	NAME OF PATENTEE OR APPLICANT	Pages/Columns/Lines Where Relevant Passages/Figures Appear	Check If Translation attached
	2L					
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JJ	2Q	Bikram Baidaya et al., "Layout Verification and Correction of CMOS-MEMS Layouts", Carnegie Mellon University, Pittsburgh.
JJ	2R	Jeffrey D. Zahn et al., "A Direct Plasma Etch Approach to High Aspect Ratio Polymer Micromachining With Applications in Biomems and CMOS-MEMS, 2002 IEEE, pgs. 137-140.
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EXAMINER	DATE CONSIDERED
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